

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Stefan BADER et al.

Serial No.: 10/696,882

Filed: October 30, 2003

For: Method for Depositing a Material on a Substrate
Wafer

Examiner: RAO, G. Nagesh
Group Art: 1722

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

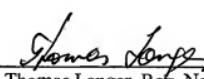
S I R:

Enclosed is an English translation of the relevant portion of reference RÖMPP Lexikon Chemie, 10th Ed., Vol. A6, pp. 4914-4915 cited in an IDS filed on October 30, 2006.

Respectfully submitted,

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